ABSTRACT

Provided is a method of manufacturing a gas supply structure for use in an electrostatic chuck apparatus having an electrostatic chuck on the upper surface side of a metal base (1), the gas supply structure being capable of eliminating contamination due to nonuniform cooling gas jetting quantities and deposition of a thermally spraying material and the like. The method of manufacturing the gas supply structure for supplying a cooling gas supplied from the lower surface side of the metal base (1) to the back surface of a substrate (W) attracted to an upper insulating layer (6) side, through a gas supply path (3) provided on the metal base (1), the method including: prior to a step of forming a lower insulating layer (4) by thermally spraying a ceramic powder on the upper surface side of the metal base (1), a step of forming an attracting electrode (5), and a step of forming the upper insulating layer (6), a step of blocking a gas supply path outlet (3a) on the upper surface side of the metal base (1) with an adhesive (8), the adhesive containing a filler made of the same material as that of the ceramic powder that is used for forming the lower insulating layer (4); and a step of opening a hole toward the gas supply path outlet (3a) of the metal base (1) after forming the upper insulating layer (6), to thereby form a through hole (9) reaching the gas supply path (3).